

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 55-003172

(43)Date of publication of application : 10.01.1980

(51)Int.Cl.

H01J 9/02

H01J 9/26

(21)Application number : 53-076093

(71)Applicant : MITSUBISHI ELECTRIC CORP

(22)Date of filing : 23.06.1978

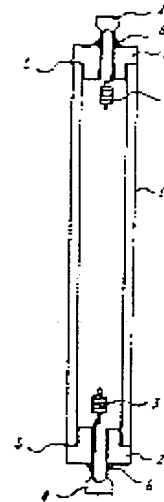
(72)Inventor : OTANI KATSUYA
TANAKA NORIHIKO

(54) METHOD OF MANUFACTURING HIGH VOLTAGE ALKALINE METAL VAPOR DISCHARGE LAMP

(57)Abstract:

PURPOSE: To eliminate scattering of electron emitting material from an electrode at sealing time by thermally treating the electrode in vacuum at the same or higher temperature as or than heat treating temperature at sealing time of the electrode before sealing step.

CONSTITUTION: After electron emitting materials is coated on the electrode coil of an electrode 3, it is calcined at 1800°C in rare gas atmosphere, and the electrode 3 is then raised at a rate of 100°C./min. to 1500°C. in vacuum atmosphere, and maintained at the same temperature for 10 minutes, then cooled to the room temperature for its heat treatment. This discharge lamp is produced by sealing the electrode thus treated in a schedule of sealing at 1400°C. for 10 minutes, and then treating a lamp fabrication step.



LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the examiner's decision of rejection or application converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of rejection]

[Date of requesting appeal against examiner's decision of rejection]

[Date of extinction of right]

Copyright (C): 1998,2003 Japan Patent Office